

DFW

AMENDMENT TRANSMITTAL LETTER

Docket No.
FIS920030360US1
Conf #3405

Application No.
10/709,406

Filing Date
05/03/2004

Examiner
Thanh T. Nguyen

Art Unit
2813

Applicant(s): **Colin J. Brodsky et al.**

Invention: **METHOD TO REDUCE PHOTORESIST PATTERN COLLAPSE BY CONTROLLED SURFACE MICROROUGHENING**

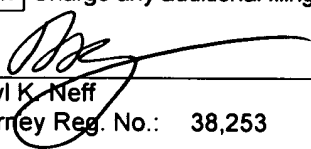
TO THE COMMISSIONER FOR PATENTS

Transmitted herewith is an amendment in the above-identified application.

The fee has been calculated and is transmitted as shown below.

CLAIMS AS AMENDED					
	Claims Remaining After Amendment	Highest Number Previously Paid	Number Extra Claims Present	Rate	
Total Claims	14	20	0		
Independent Claims	2	- 3	0		
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					
Other fee (please specify):					
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT:					

- ☒ Large Entity ☐ Small Entity
- ☐ No additional fee is required for this amendment.
- ☐ Please charge Deposit Account No. _____ in the amount of \$ _____.
A duplicate copy of this sheet is enclosed.
- ☐ A check in the amount of \$ _____ to cover the filing fee is enclosed.
- ☐ Payment by credit card. Form PTO-2038 is attached.
- ☒ The Director is hereby authorized to charge and credit Deposit Account No. **09-0458** as described below. A duplicate copy of this sheet is enclosed.
- ☒ Credit any overpayment.
- ☒ Charge any additional filing or application processing fees required under 37 CFR 1.16 and 1.17.


Daryl K. Neff
Attorney Reg. No.: 38,253

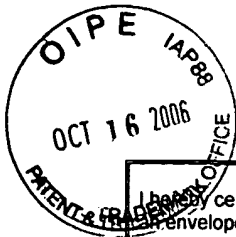
Dated: October 11, 2006

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail, in an envelope addressed to: MS Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date shown below.

Dated: October 11, 2006

Signature: 

(Daryl K. Neff)



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Dated: October 11, 2006

Signature

(Daryl K. Neff)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Colin J. Brodsky et al.

Date: **October 11, 2006**

Serial Number: **10/709,406**

Examiner: **Thanh T. Nguyen**

Filed: **May 3, 2004**

Group Art Unit: **2813**

Conf. #3405

Title: **METHOD TO REDUCE
PHOTORESIST PATTERN COLLAPSE
BY CONTROLLED SURFACE
MICROROUGHENING**

Todd M.C. Li
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Hopewell Junction, NY 12533

AMENDMENT

MS Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action dated October 11, 2006, applicants submit the following amendments and remarks for the Examiner's consideration.

FIS920030360US1